



Image AF/2877

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

JAMES BROCC STIRTON  
KEVIN R. LENSING  
HORMUZDIAR E. NARIMAN  
STEVEN P. REEVES

Examiner: Roy M. Punnoose

Group Art Unit: 2877

Att'y Docket: 2000.092400/TT5002

Customer No.: 23720

Serial No.: 10/084,987

Filed: February 28, 2002

For: METHOD OF USING HIGH YIELD  
SPECTRA SCATTEROMETRY  
MEASUREMENTS TO CONTROL  
SEMICONDUCTOR MANUFACTURING  
PROCESSES, AND SYSTEMS FOR  
ACCOMPLISHING SAME

**RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 13, 2004**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

CERTIFICATE OF MAILING  
37 C.F.R. 1.8

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:

March 3, 2004

Date

*Mary Paul*  
Signature

This paper is submitted in response to the Final Office Action dated February 13, 2004, for which the three-month date for response is May 13, 2004.

A fee in the amount of \$110.00 is believed to be due in connection with the present paper. The Director is authorized to deduct any fees required under 37 C.F.R. §§ 1.16 to 1.21, from Advanced Micro Devices, Inc. Deposit Account No. 01-0365/TT5002. In the event the monies in that account are insufficient, the Director is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.092400.

Reconsideration of the application in view of the following remarks is respectfully requested.